AMENDMENTS TO THE SPECIFICATION

Please replace paragraph [0025] with the following amended paragraph:

[0025] FIG. 1 shows schematically an optical system according to an embodiment of the the invention. The optical system comprises a first optical unit, such as a lens 10. FIG. 1 also schematically illustrates a scene in the form of an aeroplane 12 which is located outside of the optical system. The scene 12 is usually located at a large distance from the optical system such that incident electromagnetic radiation 14 from the scene 12 is incident on the ~~first optical unit 10~~lens 10 as parallel rays.

Please replace paragraph [0027] with the following amended paragraph:

[0027] The micromirror matrix unit 16 is able to be set in at least a first and a second state. In the first state, for example, all micromirror elements can be arranged in one of their end positions. If a sufficient flatness can be achieved, it is also possible that all micromirror elements are in their neutral rest position when the micromirror matrix unit 16 is set in the first state. In the second state of the micromirror matrix unit 16, the micromirror elements are arranged such that they are set in their second end positions. In FIG. 1, the micromirror matrix unit 16 is considered to be set in the first state. In this state, the micromirror matrix unit 16 reflects the electromagnetic radiation from the ~~first optical unit 10~~lens 10 such that this radiation reaches the first sensor unit 18. The micromirror matrix unit 16 is thus arranged in the beam path 20 from the ~~first optical unit 10~~lens 10 to the first sensor unit 18.

Please replace paragraph [0028] with the following amended paragraph:

[0028] The first sensor unit 18 is, according to this embodiment, of the kind where a large number of sensor elements are arranged as a two dimensional array. An example of such a sensor unit is the sensor unit BD MM 003 which is delivered by Sofradir in Chatenay-Malabry, France. Such a sensor unit may for example have 128 x 128 sensor elements. The first sensor unit 18 is thus suitably arranged in an image plane, where an image of the scene 12 is formed. According to the schematic set up which is shown in FIG. 1, this means that the first sensor unit 18 is positioned in the focal plane of the ~~first optical unit 10~~lens 10. It should however be noted that FIG. 1 only shows a schematic embodiment. There may in fact be more optical units along the beam path 20. For example, an optical unit may also be arranged in the beam path 20 between the micromirror matrix unit 16 and the first sensor unit 18.

Please replace paragraph [0033] with the following amended paragraph:

[0033] As has been described above, there is a risk that the optical system will be exposed to searching radiation. With the help of such searching radiation, an area is searched in order to discover retroreflexes. When such searching radiation enters through the ~~first optical unit 10~~lens 10, this radiation can be reflected by the first sensor unit 18 and exit through the ~~first optical unit 10~~lens 10 to be detected by the searching device. In order to reduce the probability that such a retroreflex via the first sensor unit 18 arises, the control unit 32 is suitably arranged to control the micromirror matrix unit 16 such that the incident radiation from the scene 12 only intermittently reaches the first sensor unit 18. The optical system usually works with a certain image frequency. For example, the image frequency can be 50 Hz, i.e. the first sensor unit 18 is sensed 50 times per second. However, each sensing occasion only needs to last a few ms, for example, less than 5 ms. The control unit 32 can thus control the micromirror matrix unit 16 such that the micromirror matrix 16 assumes the first state only during the time when the first sensor unit 18 is sensed. Therefore, the larger part of the time, no retroreflex via the first sensor unit 18 can occur. This reduces the risk of discovery by searching radiation.